

UV-Vis transparent conductive film based on cross-linked Ag nanowire network: a design for photoelectrochemical device

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Supplementary Data

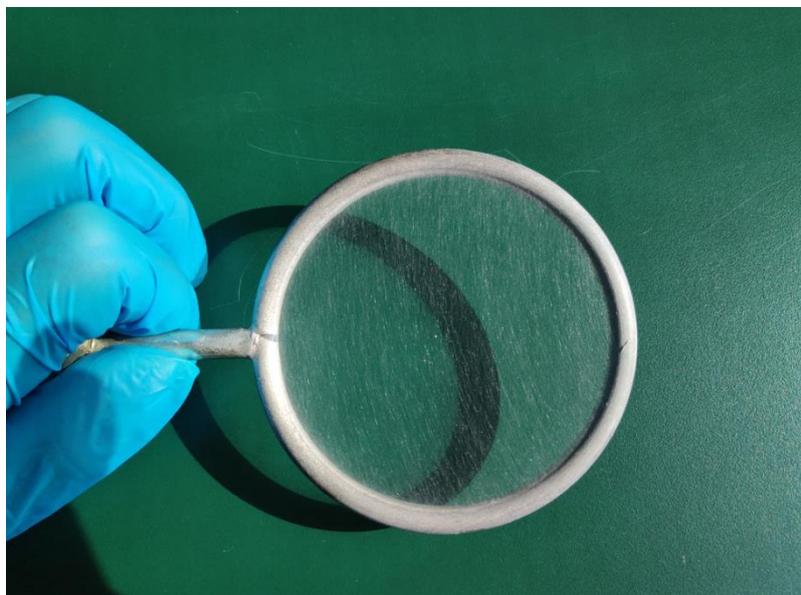


Figure S1. The Ag layer under side light illumination.

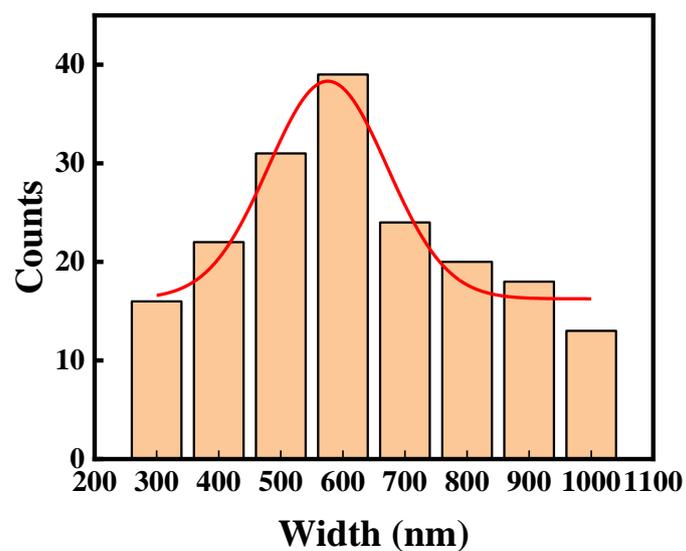


Figure S2. The counts under different width of AgNWs acquired by SEM image.

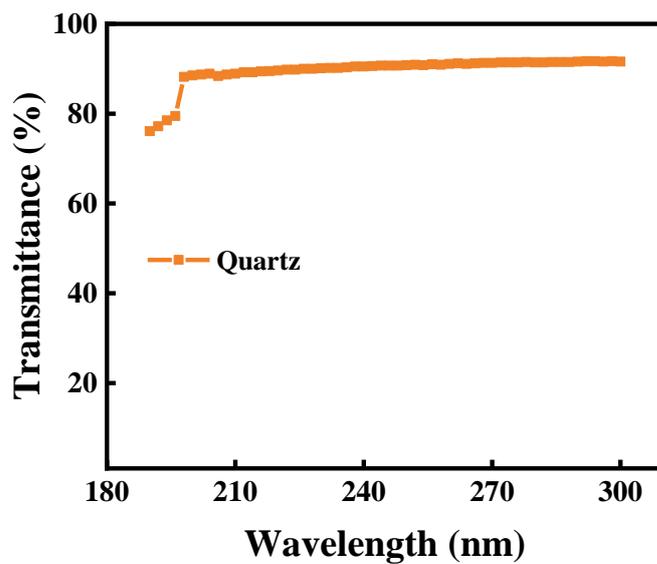


Figure S3. The transmittance of quartz from 190 to 300 nm.

Table S1. Thickness of TiO₂ layer, sheet resistance and transmittance versus different sputtering time.

Sputtering time (min)	1.5	3.0	4.5	6.0	7.5	9.0	10.5	12.0
Thickness of TiO ₂ (nm)	27.75	55.5	83.25	111	138.75	166.5	194.5	222
Sheet resistance (Ω/sq)	3.662	5.373	6.903	9.478	11.775	15.493	21.083	27.309
Transmittance (%)	46	41.5	37.3	33.6	26.7	21.2	13.6	6.9

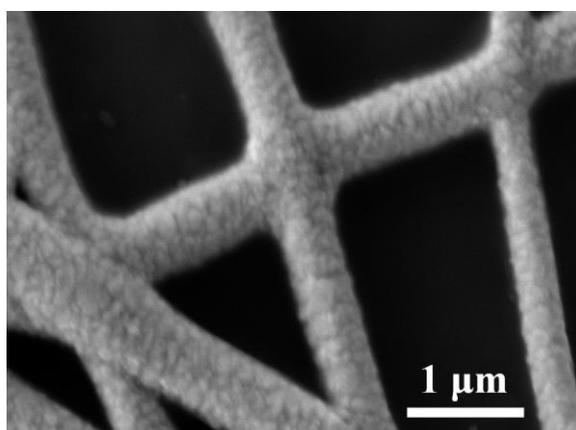


Figure S4. The cross-linked intersection of different AgNWs.



Figure S5. Diagram of 3M-Scotch tape testing.